

Ultra-Widely Tunable VCSELs

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Outline

- Description of collaboration and foundational work
- Tunable laser technologies and MEMS-VCSEL details
- Introduction to optical coherence tomography (OCT)
- 1310 nm MEMS-VCSELs with a 150 nm tuning range
- 1060 nm devices with a 100 nm tuning range
- Summary of results and path forward

Collaborative Partners

- Praevium Research



- commercializing high functionality, miniaturized opto-electronic devices including broadband sources for OCT

- Advanced Optical Microsystems



- optical microsystems design and fabrication consulting services (day job: Universitätsassistent, VCQ, Uni. Vienna)

- MIT, Fujimoto Group



- original inventors and pioneers of OCT, validating device performance for medical imaging applications

- Thorlabs



- responsible for investigating manufacturability and scalability of device designs; commercialization of final product



Commercial MEMS-VCSEL OCT System

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High-Speed MEMS-Tunable VCSEL for Swept Source OCT

MEMS-Tunable VCSEL for High-Speed OCT Imaging

*Coherence Lengths
Greater than 50 nm*



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[MEMS-VCSEL](#)

[Imaging Capabilities](#)

[Tutorial](#)

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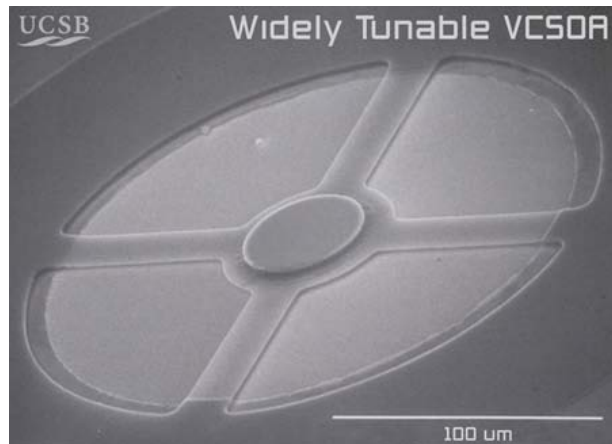
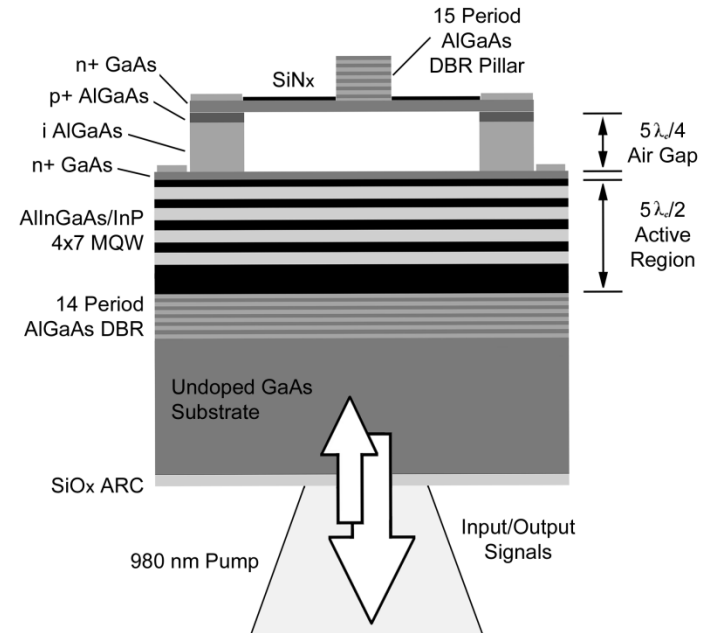
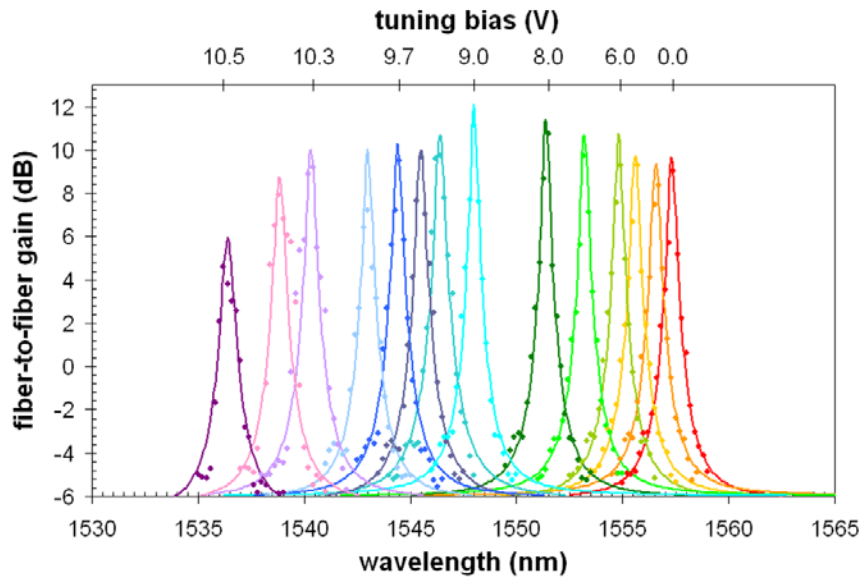
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Commercial MEMS-VCSEL OCT System



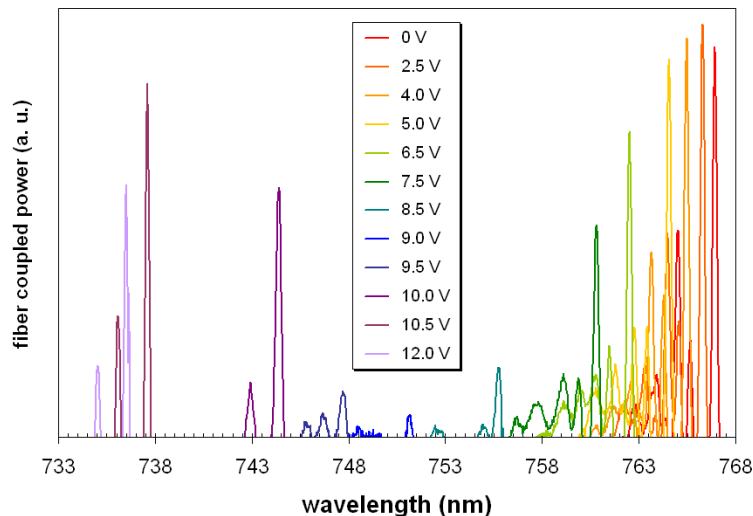
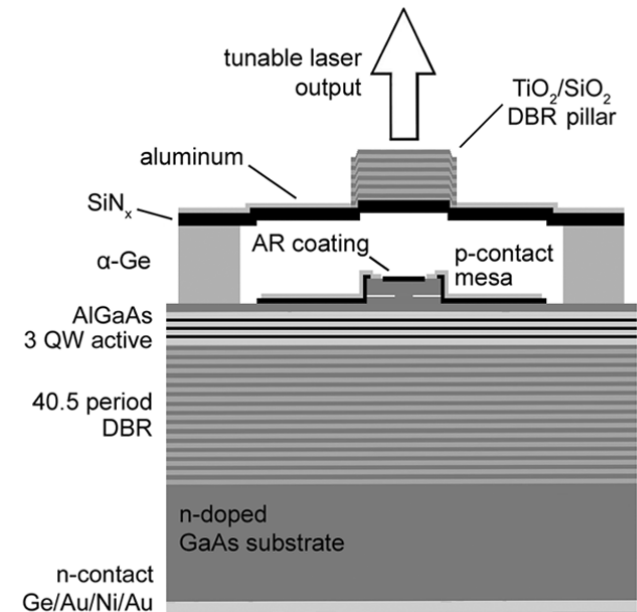
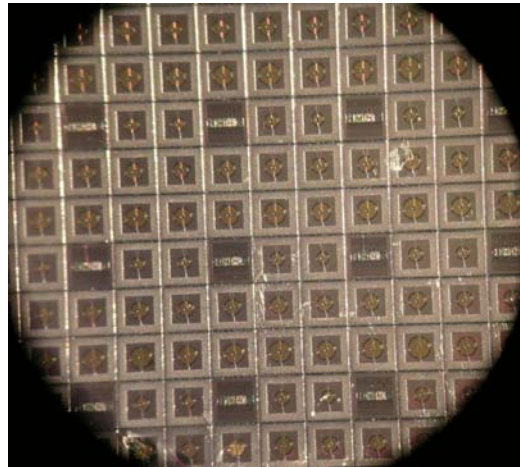
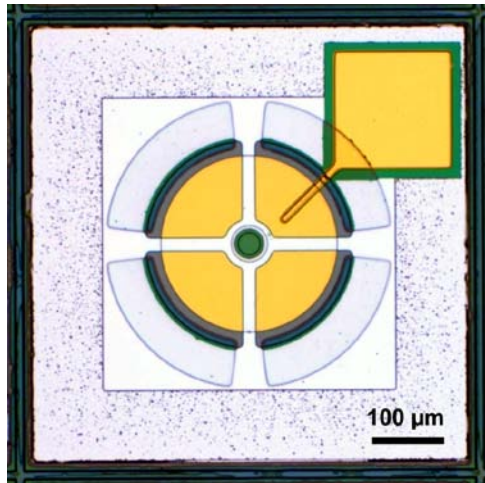
Dissertation, UCSB: MEMS-Tunable VCSOAs



Tunable Vertical-Cavity Amplifiers:

- Resonant Cavity optical preamplifiers
- Wafer-bonded GaAs/InP/GaAs cavity structure
- 28 AlInGaAs QWs with epitaxial MEMS DBR
- ~10 dB fiber-to-fiber gain over 21 nm
- Fiber-coupled gain of 11.2 dB (18.2 dB on chip)

Postdoc, LLNL: MEMS-Tunable VCSELs



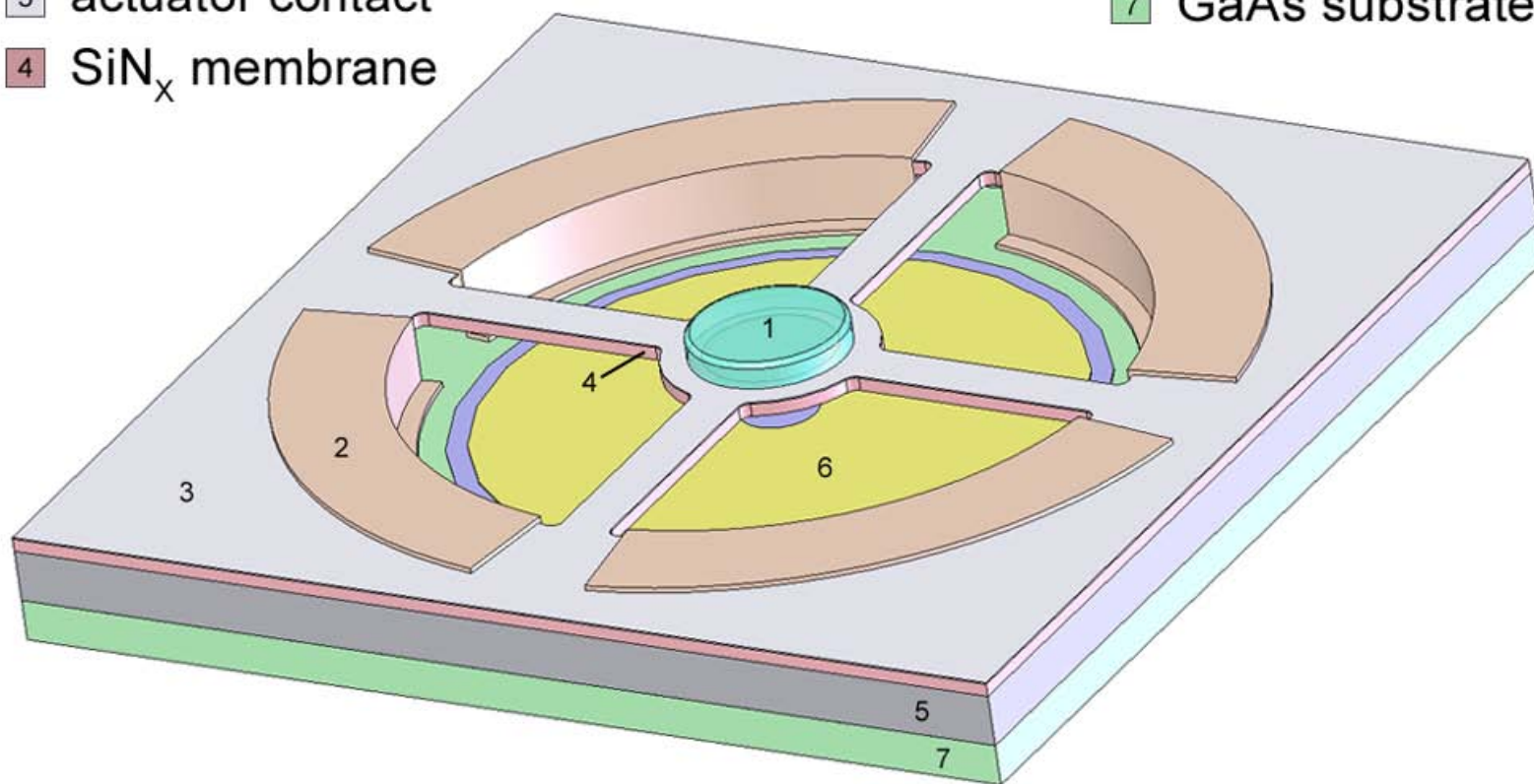
Short Wavelength MEMS-VCSELs:

- Electrically injected ~760 nm tunable VCSEL
- Monolithic AlGaAs epi with graded n-DBR
- Oxide aperture for current/mode confinement
- Extended cavity design (intra-cavity ARC)
- All dielectric suspended mirror structure

Postdoc, LLNL: MEMS-Tunable VCSELs

- 1 TiO₂/SiO₂ DBR
- 2 undercut protection
- 3 actuator contact
- 4 SiN_x membrane

- 5 amorphous Ge
- 6 actuator ground
- 7 GaAs substrate



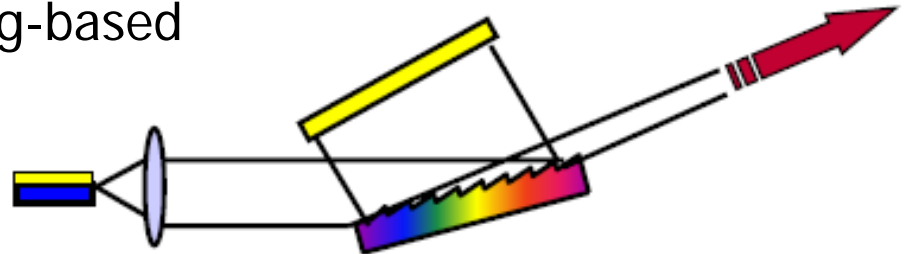
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Select Tunable Laser Technologies

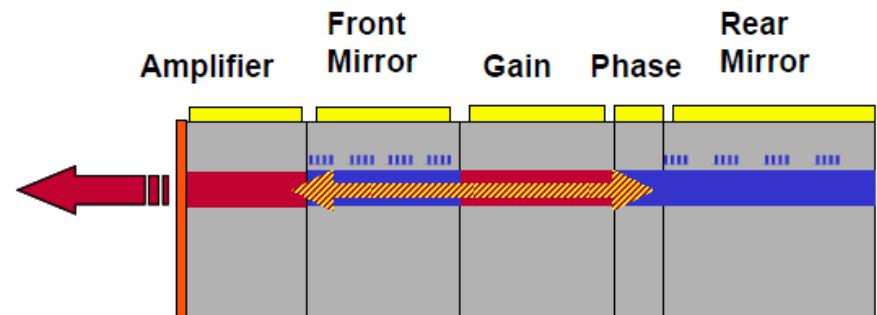
External Cavity Tunable Laser (ECTL)

- Diode gain medium with grating-based wavelength selective feedback
- Tuning range ≥ 100 nm
- Tuning speeds ≤ 100 kHz
- Wide tunability but slow tuning speed



Sampled-grating distributed Bragg reflector (SGDBR)

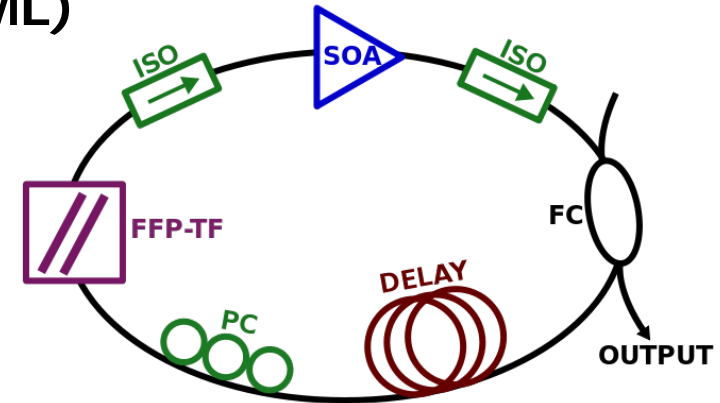
- Overlap of reflectance comb to select lasing wavelength
- Switching speeds in ns range
- Typical tuning range of ~ 50 nm
- Mode hops and complex control



Select Tunable Laser Technologies

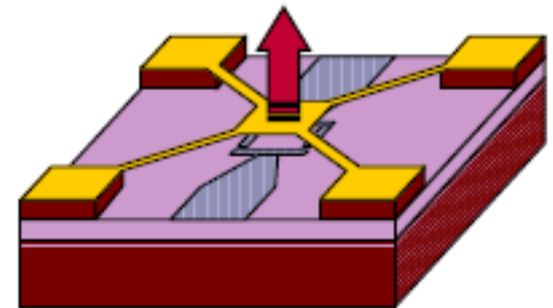
Fourier domain mode locked laser (FDML)

- Ring laser with intra-cavity tunable filter
- 160 nm tuning range demonstrated
- MHz sweep rates possible
- Wide tuning but with fixed sweep rate, limited wavelength accessibility

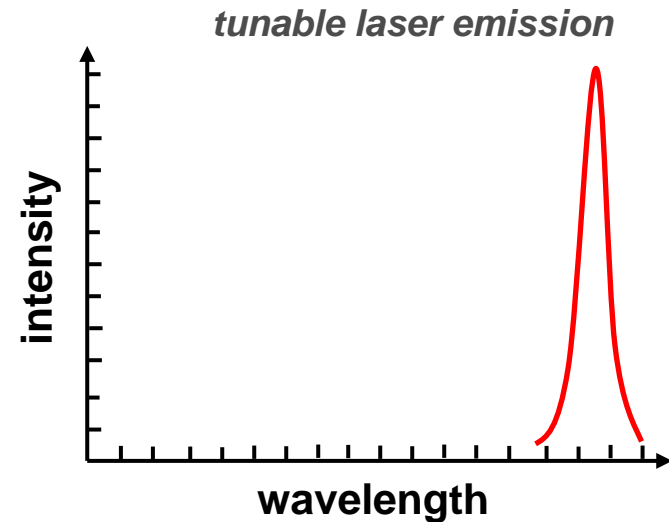
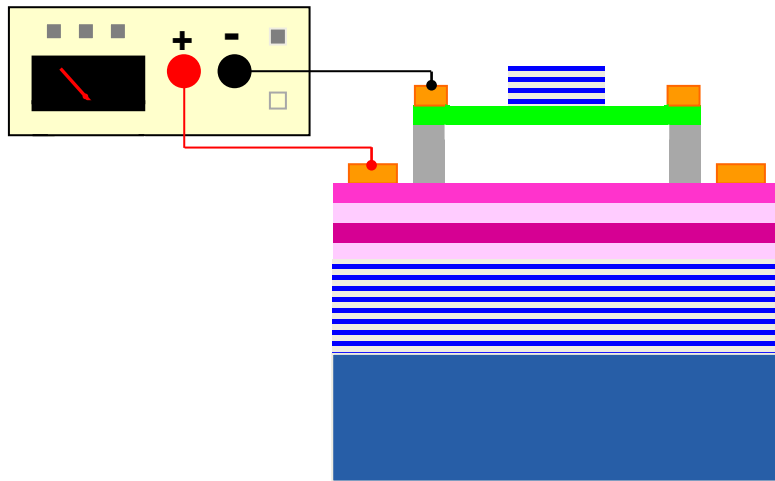


MEMS-tunable VCSEL

- Microcavity laser with suspended mirror
- >100 nm tuning recently demonstrated
- Sweep rates ~1 MHz (MEMS-limited)
- Compact devices requiring a simple control scheme; potentially low cost fabrication



MEMS-Tunable Surface-Emitting Lasers

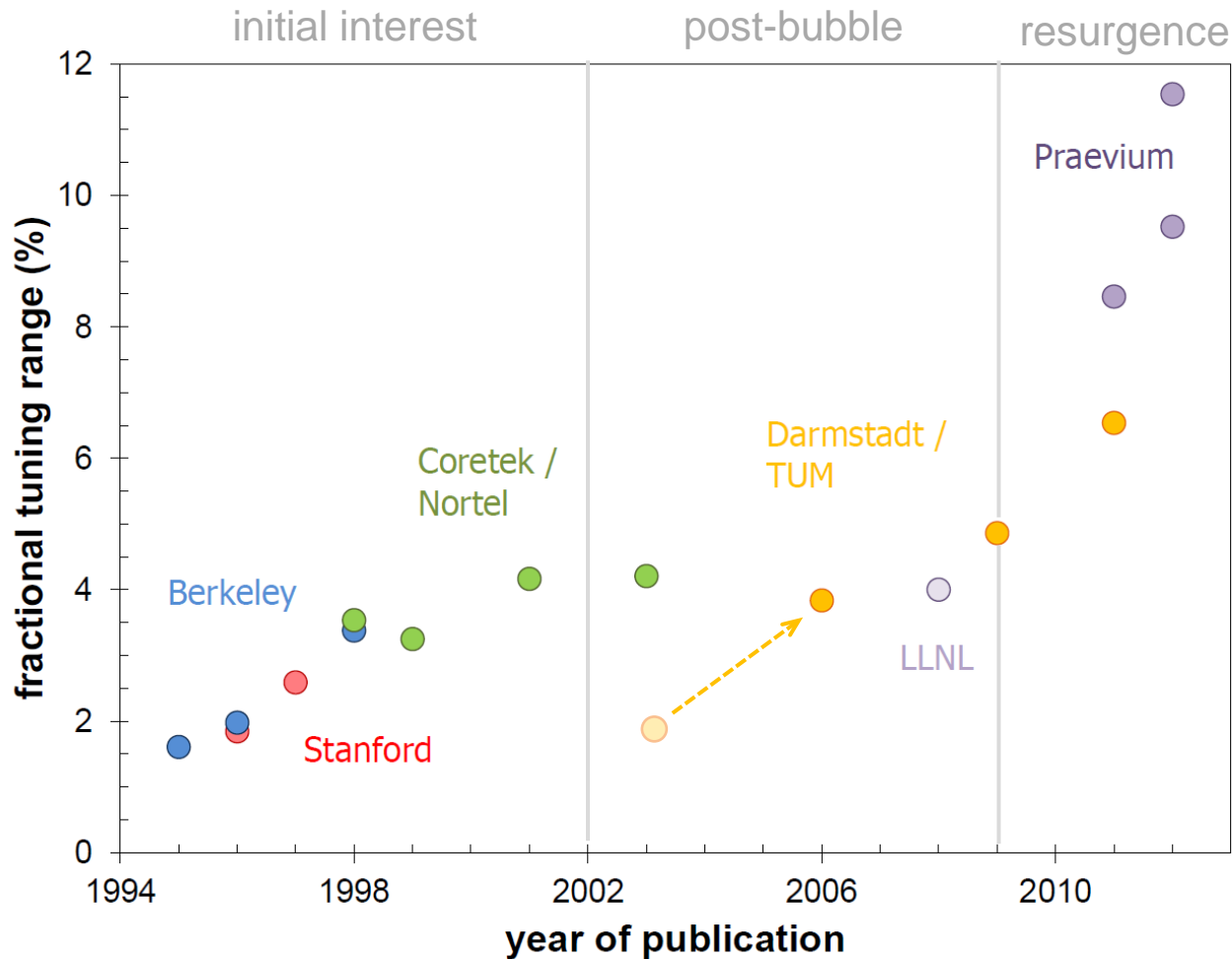


- Vertical orientation lends itself well to MEMS integration
- Bottom DBR and active region identical to fixed lasers ("half-VCSEL")
- Top mirror is suspended, deflection alters axial cavity length
- Broad tunability enabled by wide gain spectrum & stopband, large FSR
- Rapid wavelength scanning possible with properly designed actuator

Historical Overview of MEMS-VCSELS

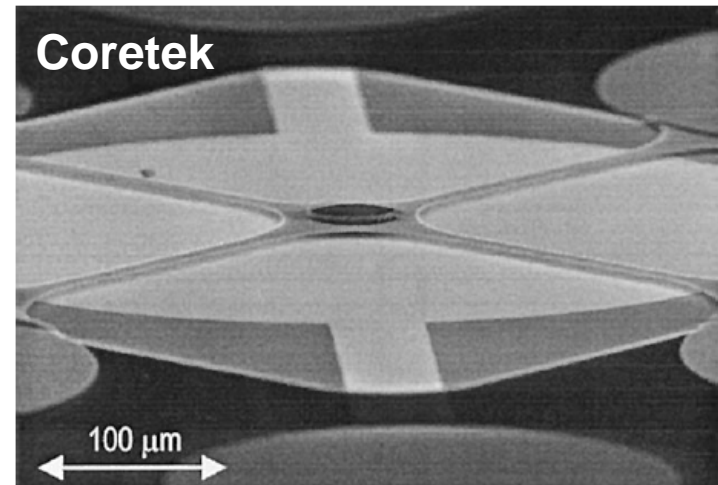
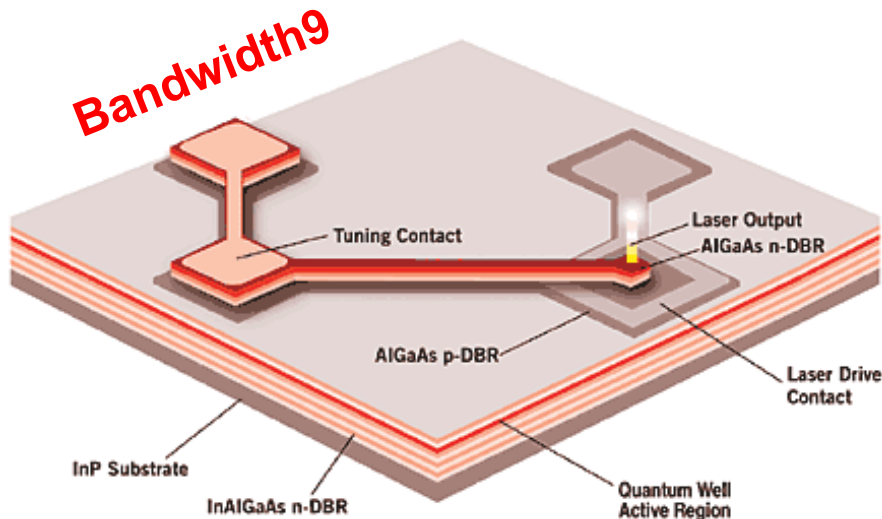
- First proposed by B. Pezeshki and J. S. Harris, Jr.
 - U.S. Patent 5,291,502 (filed on September 4, 1992)
- First devices demonstrated in 1995 (M.S. Wu, et al.)
 - key players: Stanford and Berkeley (Chang-Hasnain & Harris)
- Commercialization of telecom devices (BW9, Coretek)
 - Nortel purchases Coretek for \$1.43 billion in stock (3/2000)
- Bubble bursts, MEMS-VCSEL dark ages (~2002-2009)
 - TUM/Darmstadt collaboration continues progress
- Recent resurgence: rapid increase in fractional tuning and revitalized commercialization efforts (BW10!)

Fractional Tuning Range Versus Time



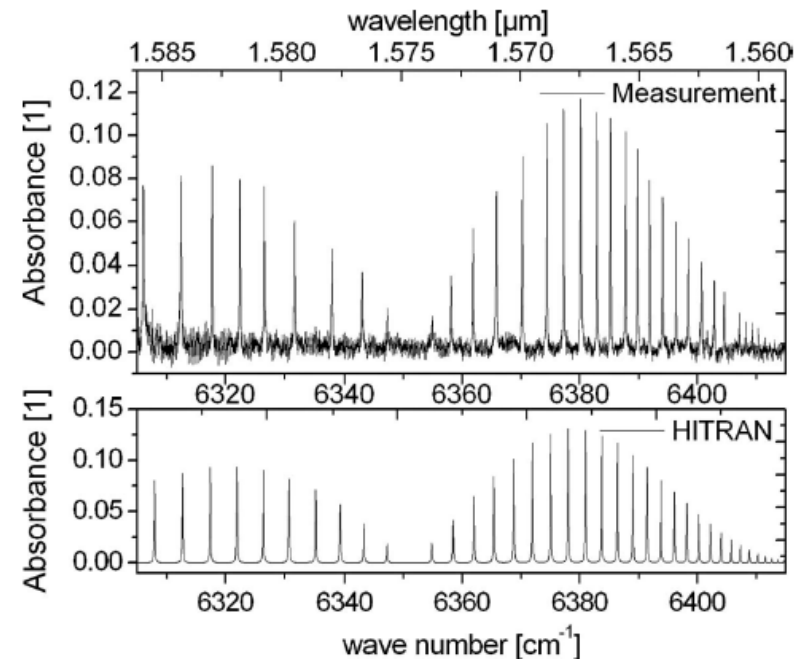
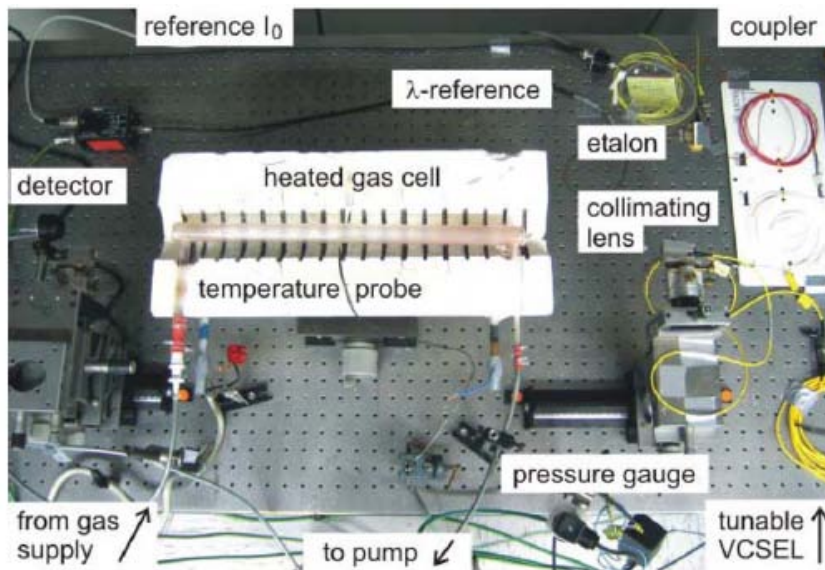
Applications of MEMS-VCSELs

- Initial focus on telecommunications, particularly with the development of long-wavelength devices
 - potential uses: networks employing wavelength division multiplexing (WDM), laser spares, temperature drift compensation
 - “Tunable Long-Wavelength Vertical-Cavity Lasers: The Engine of Next Generation Optical Networks?” J.S. Harris, JSTQE Nov. 2000



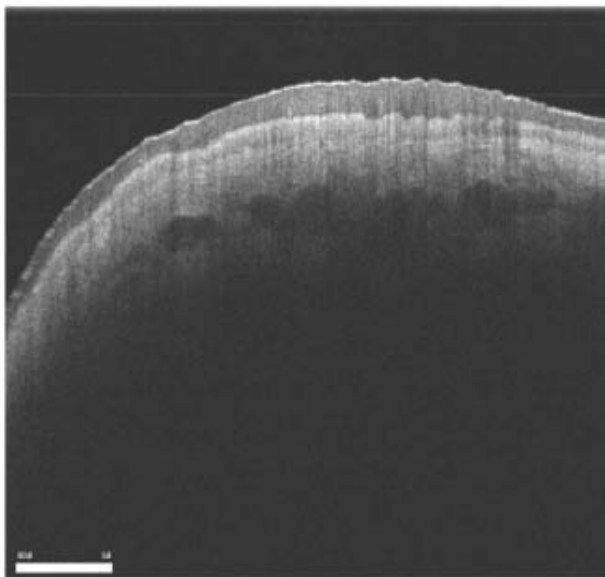
Applications of MEMS-VCSELs

- Gas spectroscopy (CO, CO₂, NH₃, etc.)
 - tunable VCSELs enable broadband continuous single mode tuning with a narrow dynamic linewidth (~200 MHz) for trace gas detection
 - “Simultaneous spectroscopy of NH₃ and CO using a >50 nm continuously tunable MEMS-VCSEL” Kögel et al. IEEE Sensors 2007

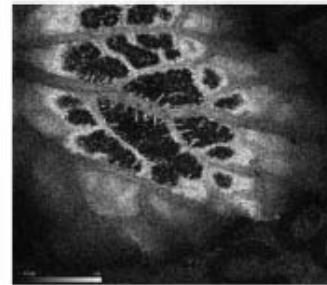


Applications of MEMS-VCSELs

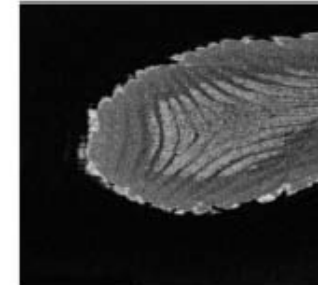
- Optical Coherence Tomography (OCT)
 - optical medical imaging technique requiring broad and rapidly tunable laser systems; typical operating wavelengths 850-1310 nm
 - "OCT imaging up to 760 kHz using single-mode 1310 nm MEMS-tunable VCSELs with >100 nm tuning range" Jayaraman CLEO 2011



60kHz axial scan rate



200kHz axial scan rate



400kHz axial scan rate

Outline

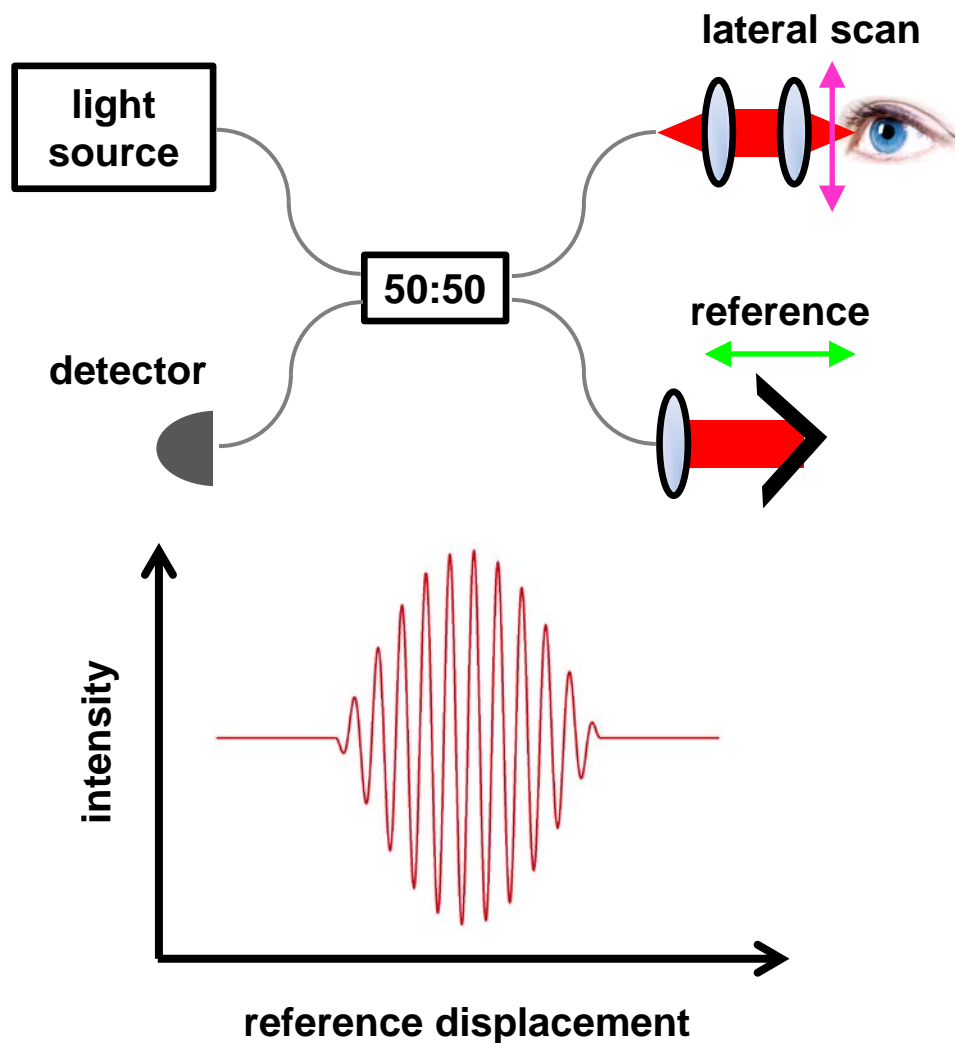
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Optical Coherence Tomography (OCT)

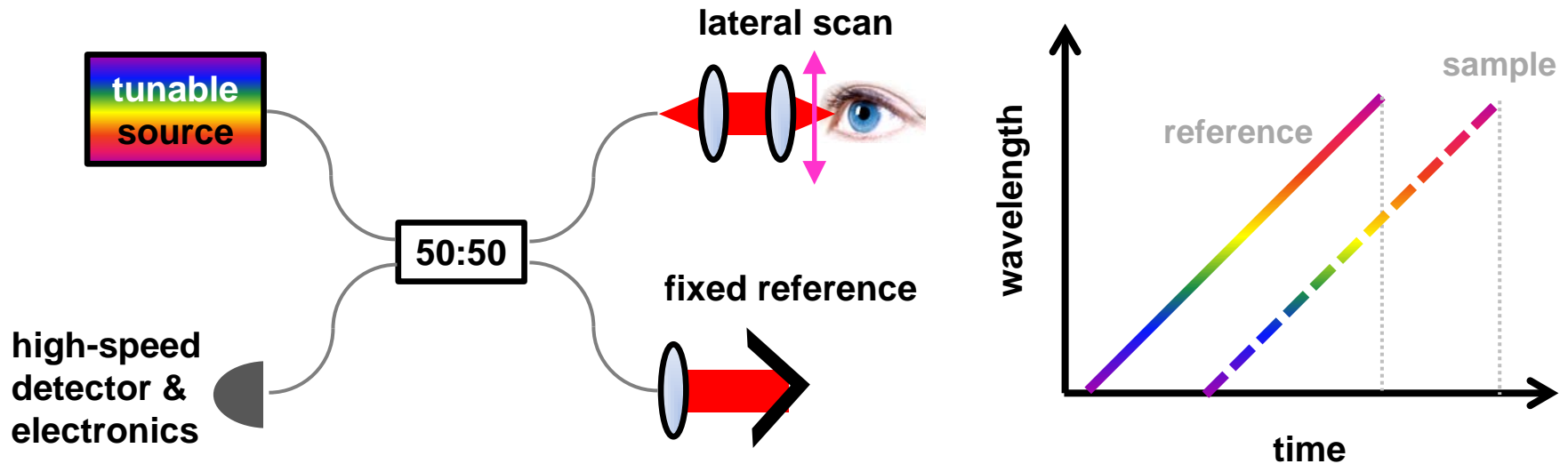
- “Optical Ultrasound” emerging medical imaging technology
- Enables real-time μm -scale subsurface and 3D imaging
- Imaging is performed by measuring the echo time delay and intensity of back-reflected/backscattered NIR light
- Typical imaging depths are from ~ 1 mm to >10 mm, depending on the scattering level of imaged tissue, the imaging mode, and light source coherence length
- Spatial resolution is **10-100 \times** better than magnetic resonant imaging (MRI), computed tomography (CT), and ultrasound
- Applications include ophthalmic and vascular imaging, with trials underway for dentistry, dermatology, and cancer detection

Basic OCT Operating Principles (Time Domain)

- Broadband (low coherence) light source yields high-contrast interference fringes when path lengths match
- Peak fringe intensity yields reflectivity for a given depth, scanning an optical delay line (pathlength ranging) yields tissue characteristics as a function of depth
- Lateral scanning of the probe creates a 3D map of sample

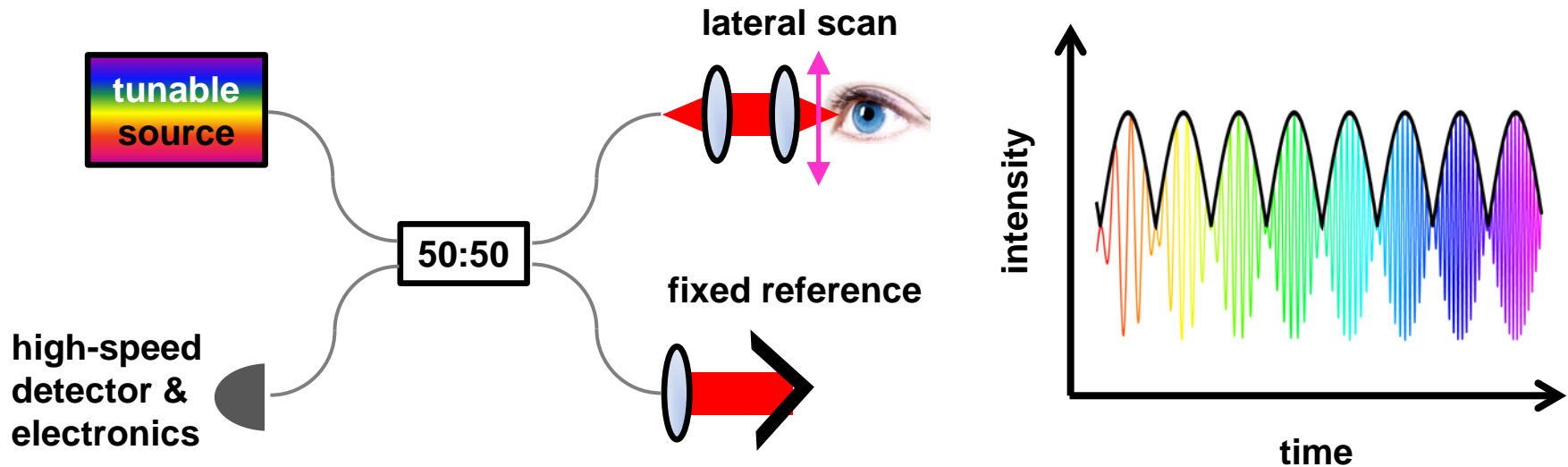


Improved Imaging Rates: SS-OCT



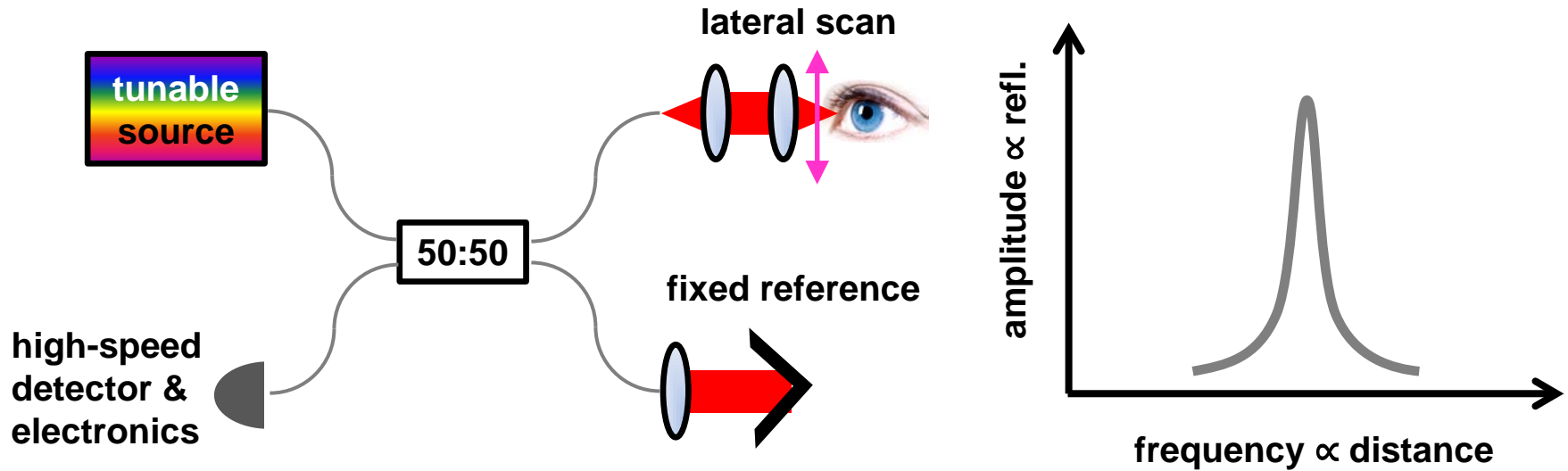
- Beat frequencies correspond to different delays, thus depths, in sample
- Fourier transform yields profile of reflection as a function of depth
- Ideal SS-OCT source requirements:
 - widely tunable (>100 nm) with narrow instantaneous linewidth
 - rapid (MHz) sweep rate with well behaved dynamics (critically damped)
 - output power levels from 30-50 mW (external amplification required)

Improved Imaging Rates: SS-OCT



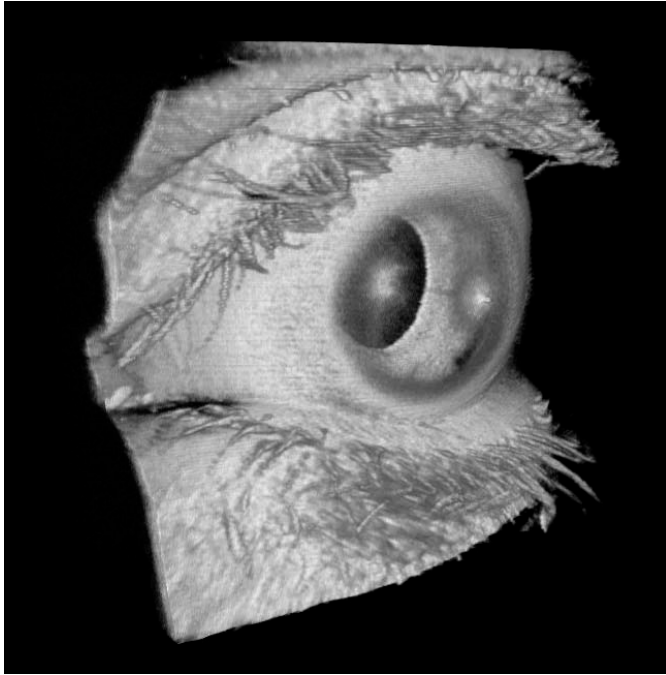
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Example Imaging Results

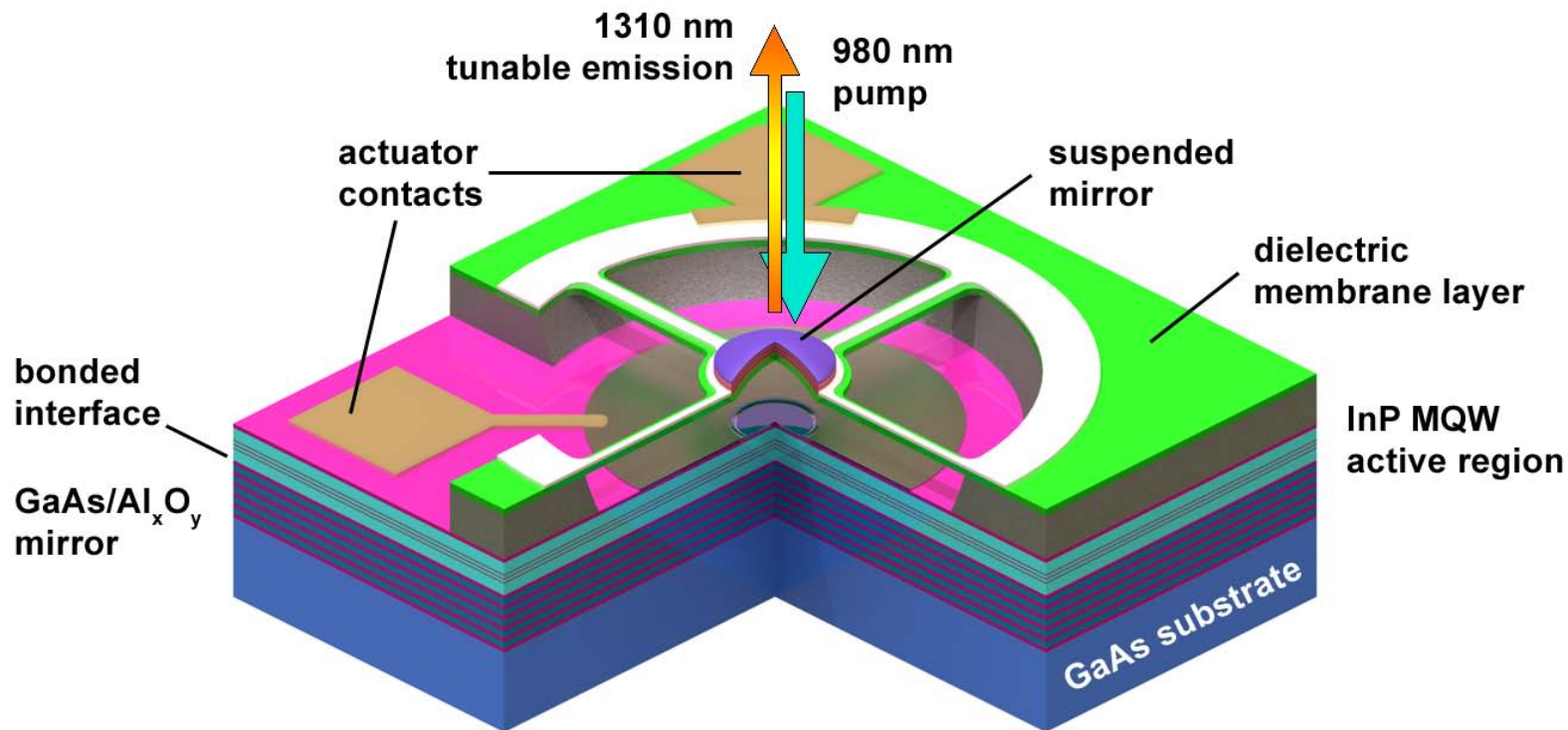


- Volumetric OCT imaging of the anterior eye and retina
- Arbitrary cross-sections can be extracted from 3D dataset
- More details to follow in discussion of MEMS-VCSEL performance

Outline

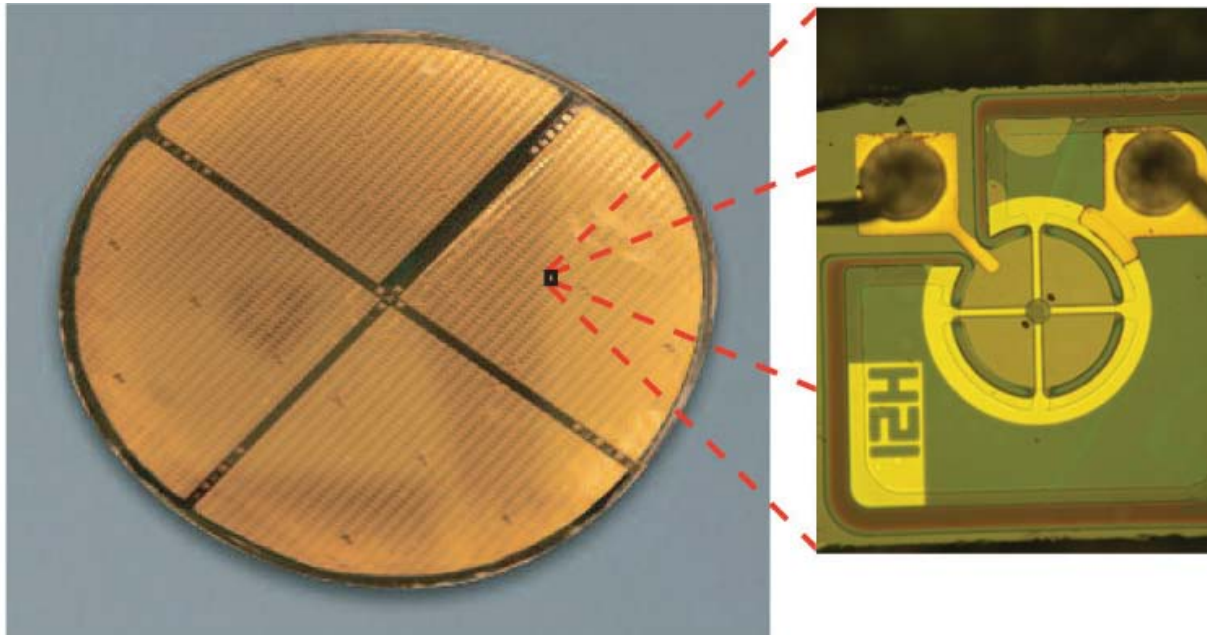
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Ultra-Widely Tunable 1310 nm MEMS-VCSEL



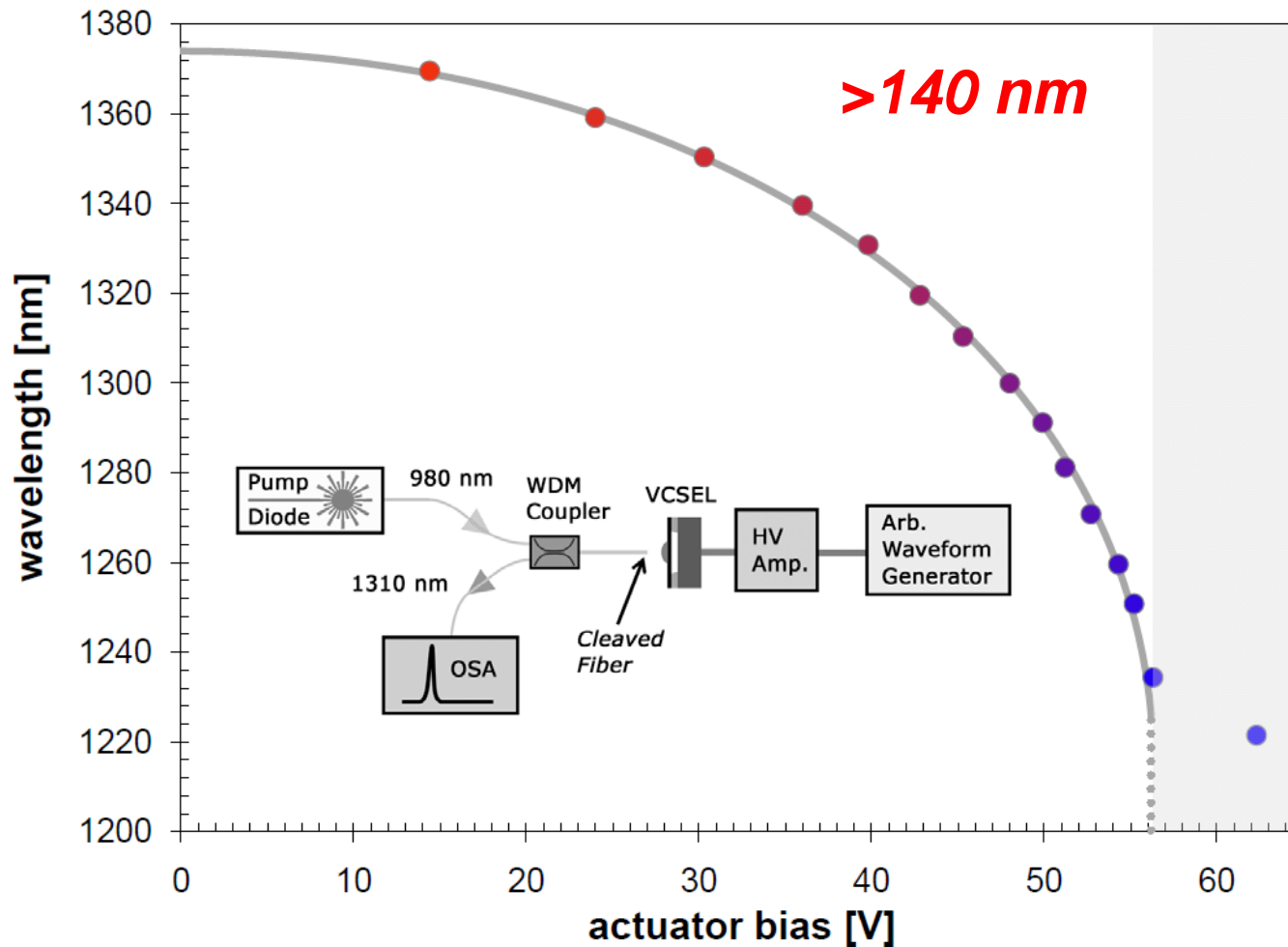
- AlInGaAs MQW active and GaAs/Al_xO_y DBR combined by wafer bonding
- Optimized for optical pumping at 980 nm, short cavity for large FSR
- Dielectric suspended top mirror with integrated electrostatic actuator

Wafer-Scale MEMS-VCSEL Manufacturing

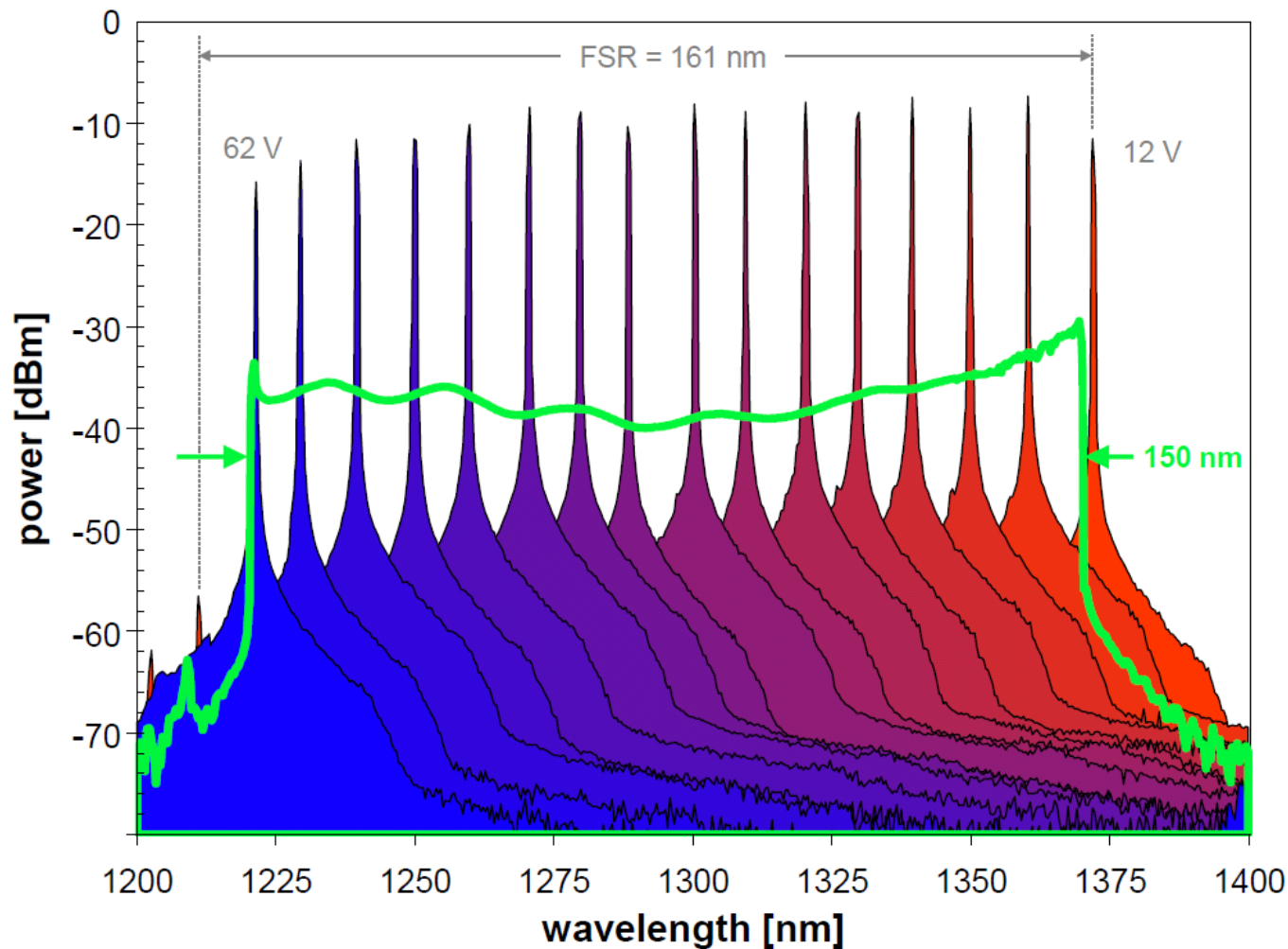


- Robust fabrication procedure developed for suspended mirror structure
 - dry release, no polymer sacrificial films or need for critical point drying
- All-dielectric process employing low temperature ($< 300\text{ }^{\circ}\text{C}$) deposition
 - enables development of lasers at a variety of emission wavelengths

Ultra-Wide Static Tuning Response



Overlaid Spectra & Dynamic Tuning



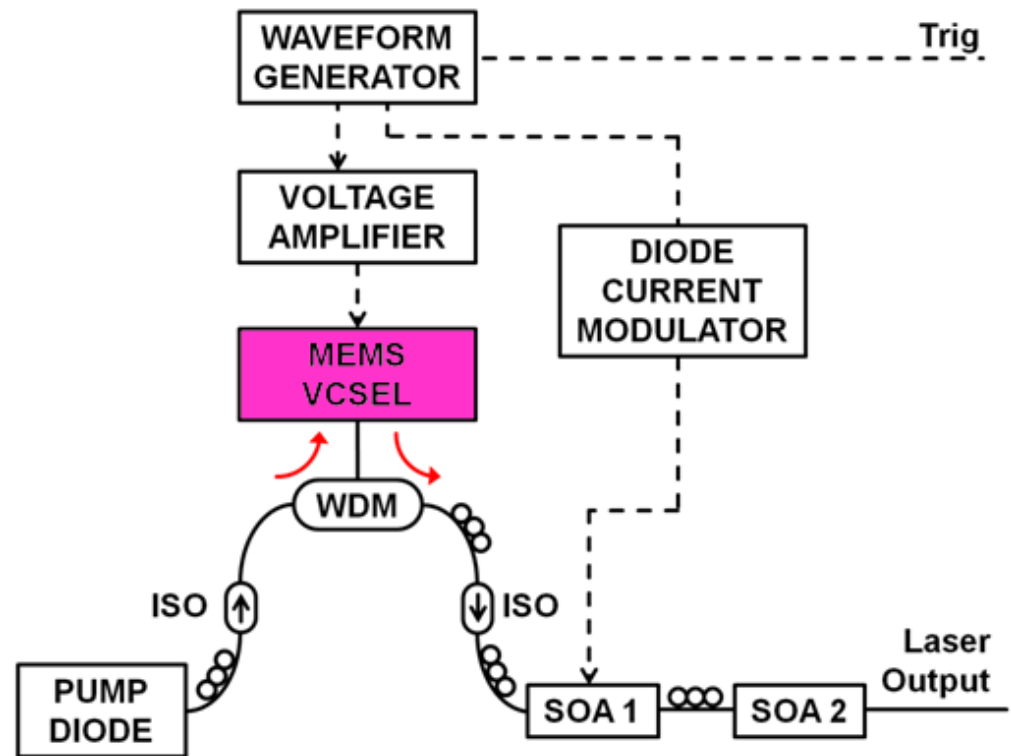
MEMS-VCSEL-Based OCT Imaging

- Fiber-coupled VCSEL
 - 1310 nm: reduced scatter
increased penetration
- WDM coupler and short-wavelength pump diode
- Arbitrary waveform generator and amp driver
- External amplification boosts power to 20 mW
- SOAs may be modulated for additional control knob on laser sweep rate



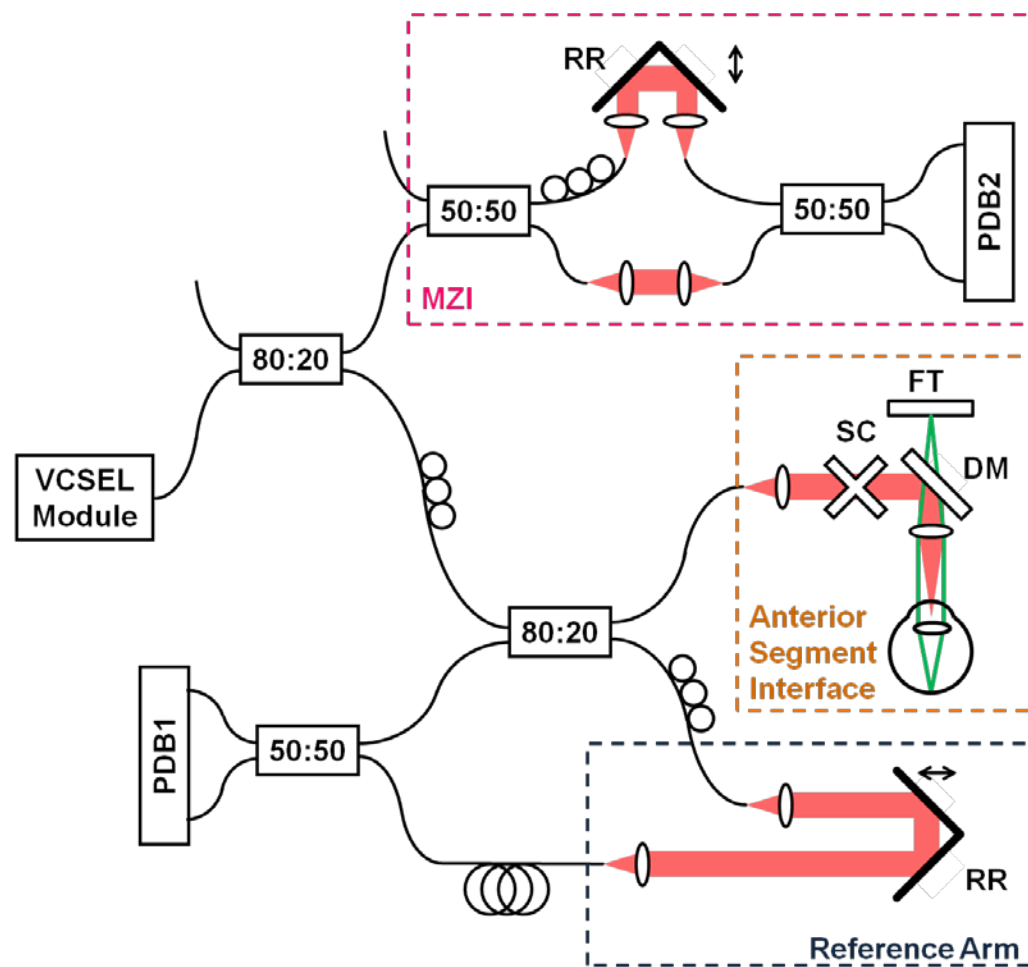
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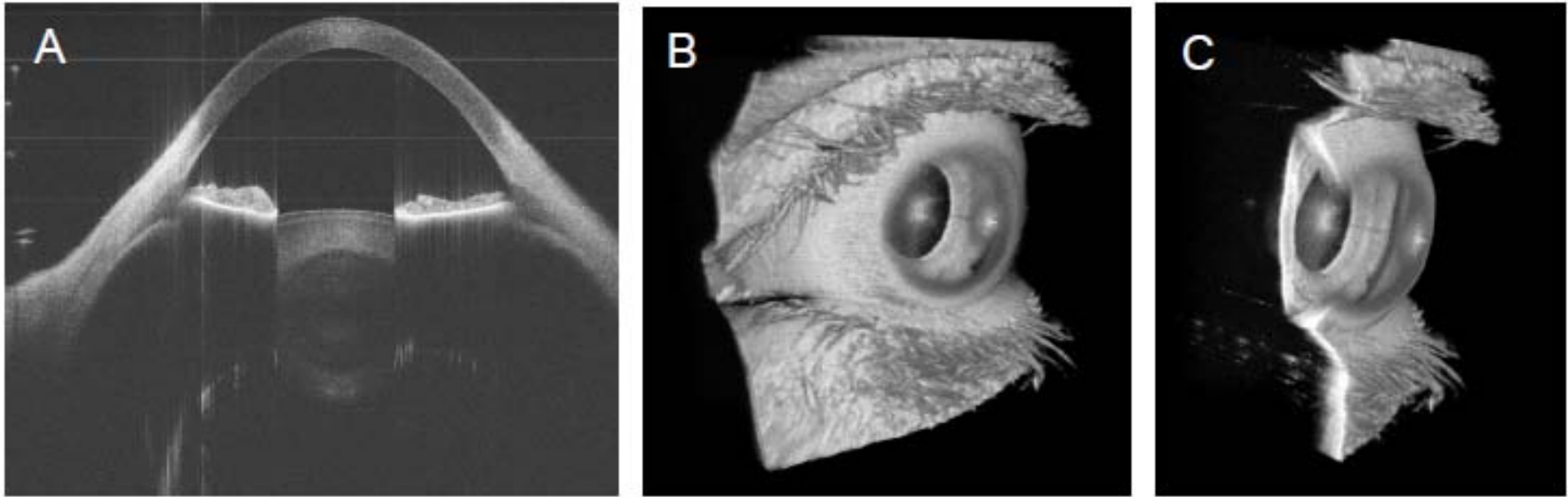


MEMS-VCSEL-Based SS-OCT Imaging

- Mach-Zehnder (MZI) for calibration fringe capture
 - interferometer records instantaneous laser frequency
- Lower path: interference between reflected probe and reference
 - beat note generated in frequency domain
 - Fourier-transform reconstructs reflectivity depth profile

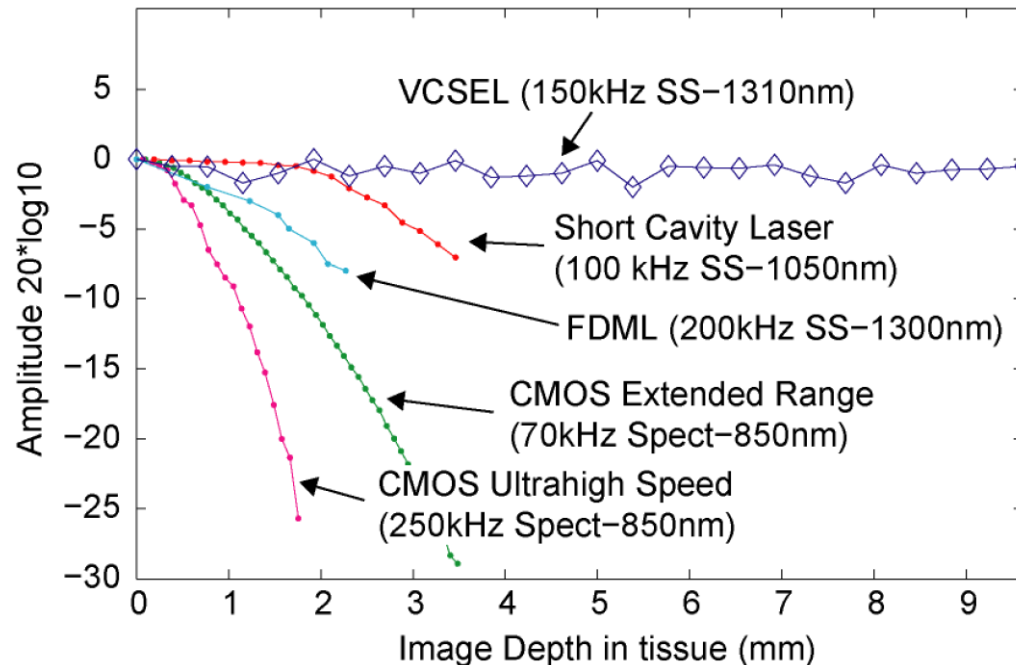


1310 nm Anterior Segment Imaging



- (A) High resolution cross-sectional image of the anterior eye
 - 10^3 axial scans over 21 mm obtained at 10^5 axial scans / second
- (B) Rendering of a 400×400 axial scan volume of the anterior eye
- (C) Cutaway of the volume in (B) showing interior features of the iris

State-of-the-Art Imaging Depth

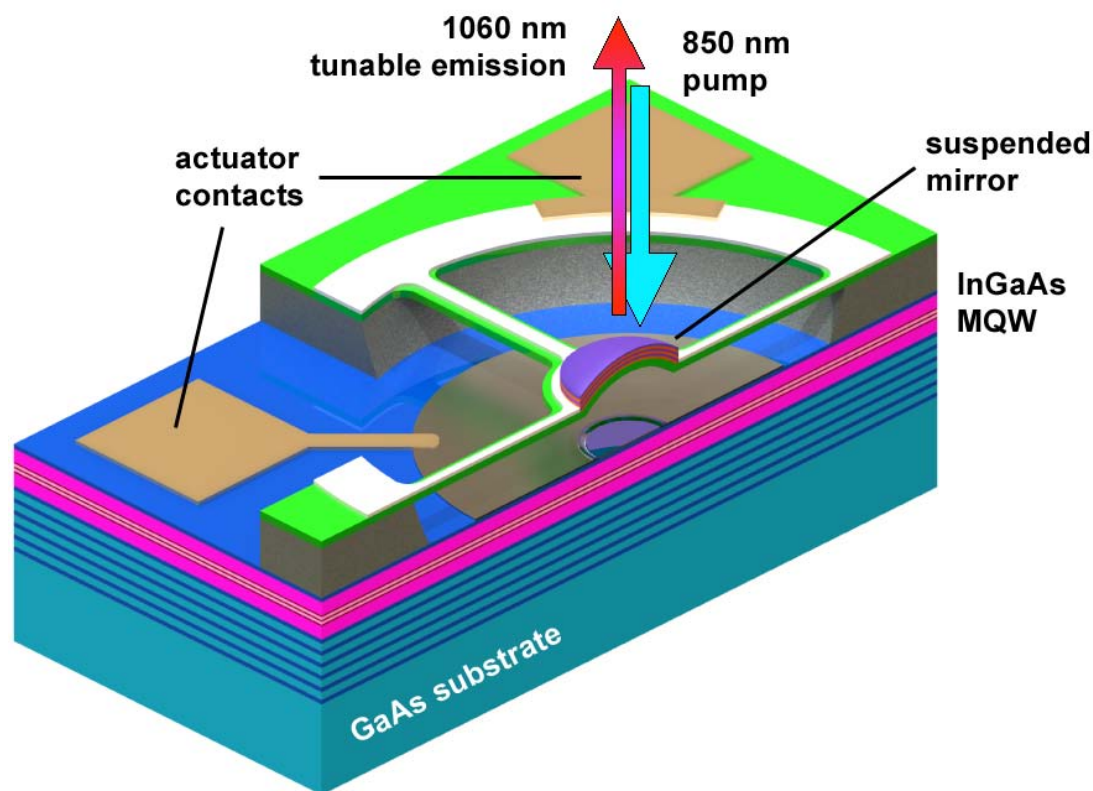


- Narrow instantaneous linewidth enables deep ($\gg 1$ cm) imaging
 - enhanced spectral resolution \rightarrow longer imaging depth in SS-OCT
- Competing laser sources suffer from multimode operation with tuning

Outline

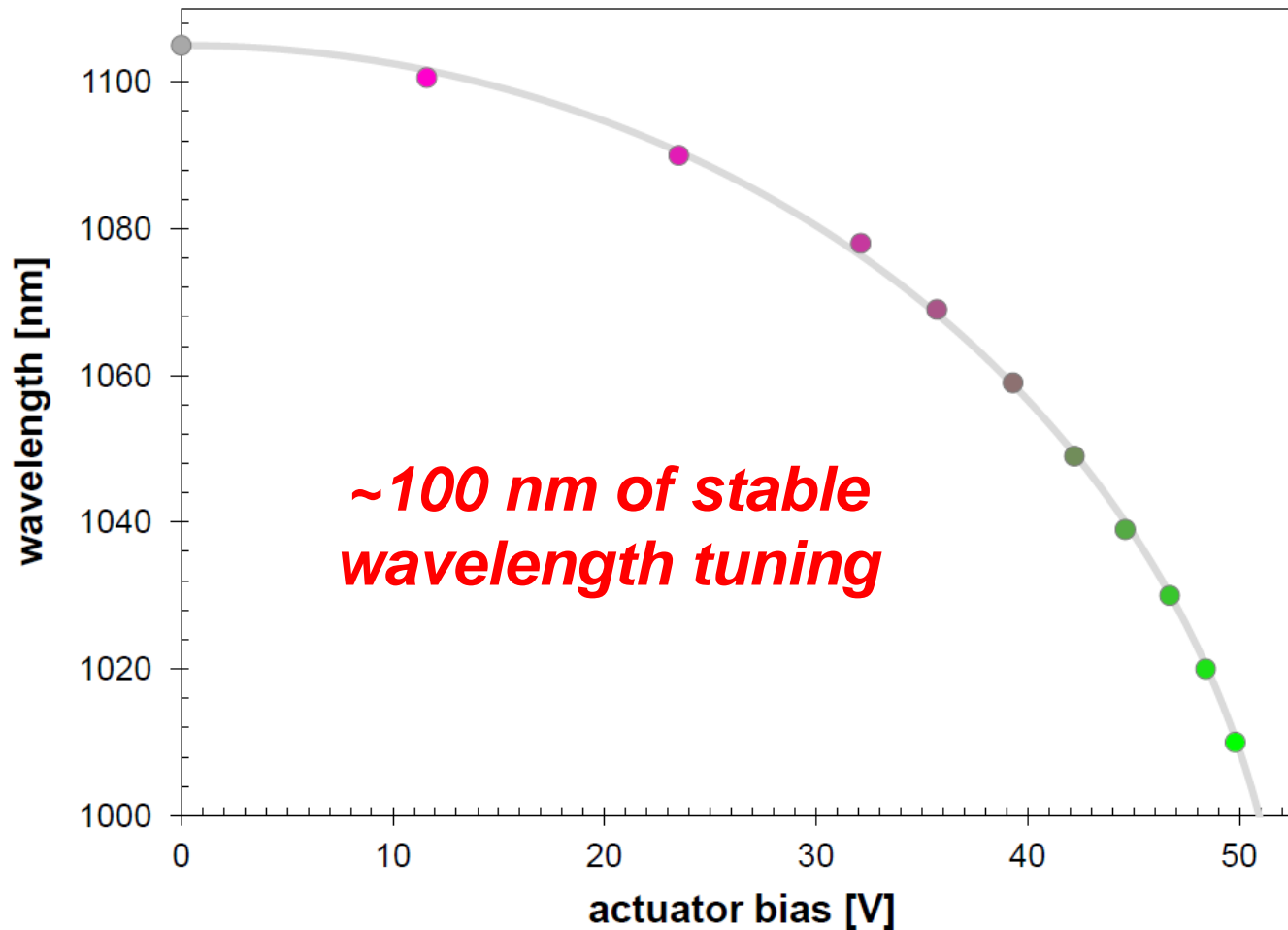
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Ultra-Widely Tunable 1060 nm MEMS-VCSEL

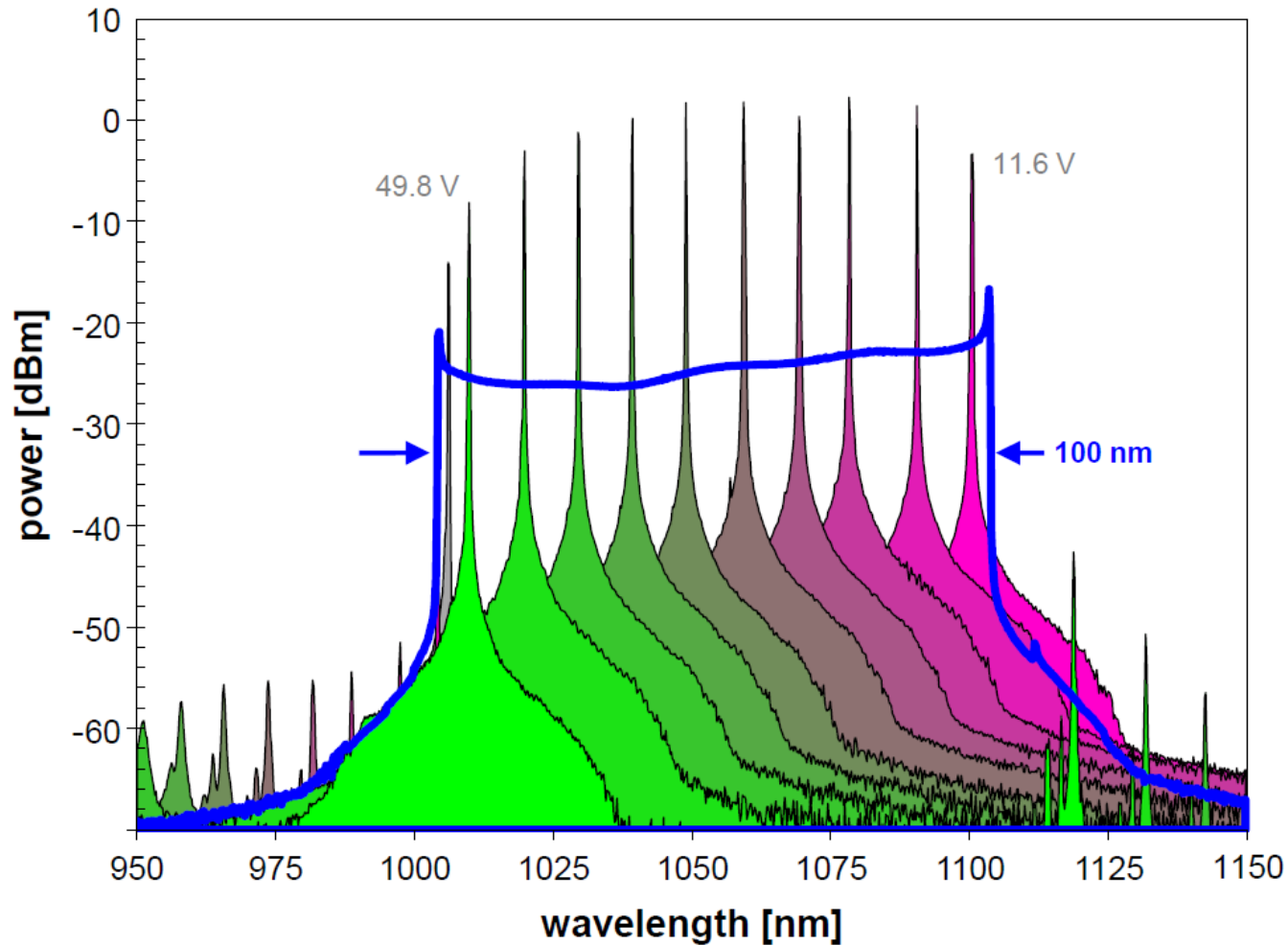


- Monolithic “half VCSEL”
 - single epitaxial growth
- InGaAs MQW active
- Broadband reflectors
 - fully-oxidized bottom DBR (GaAs/Al_xO_y)
 - dielectric suspended mirror structure
- Integrated actuator optimized for critically damped freq. response
- Aim: retinal imaging

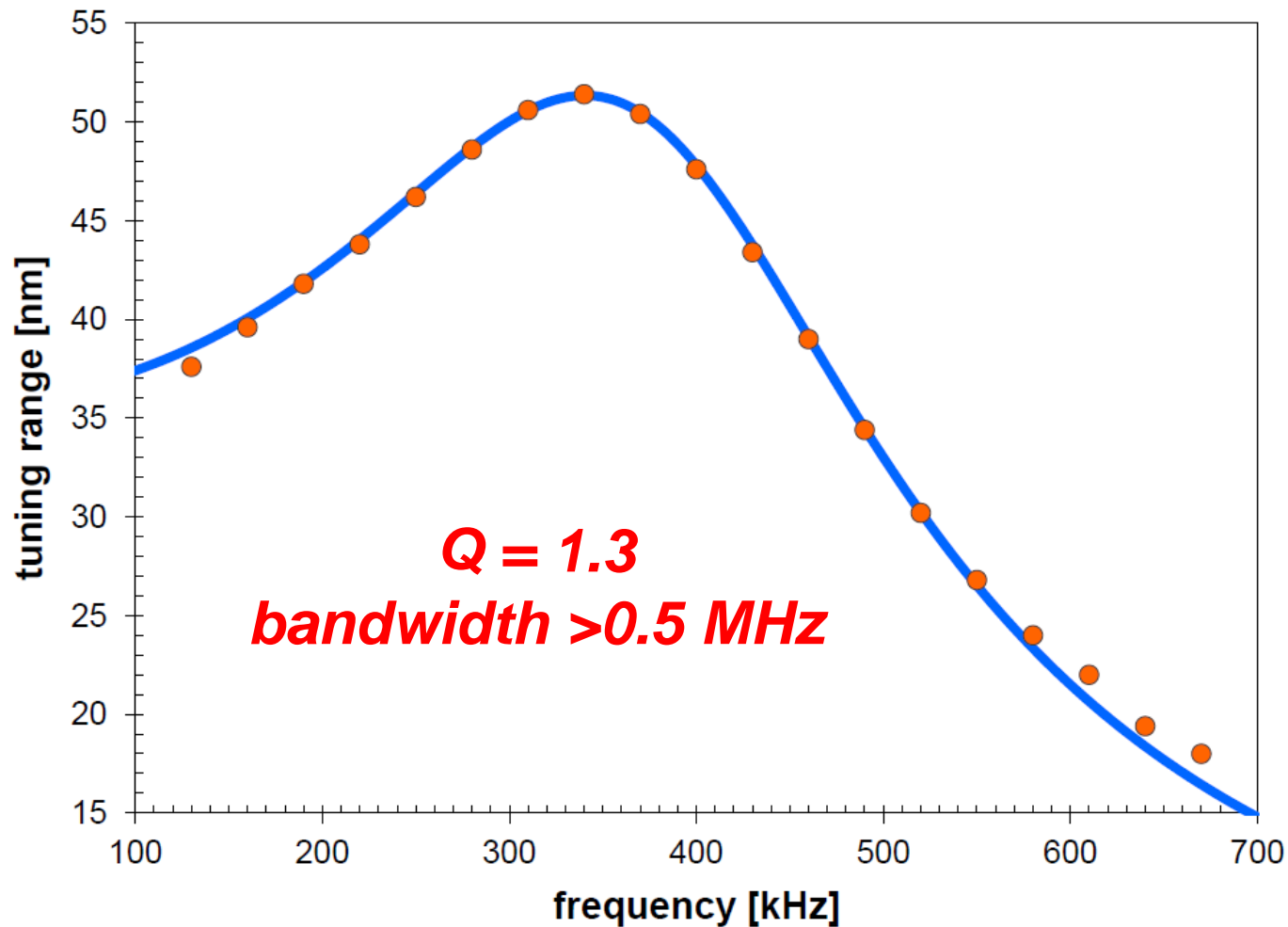
Static Tuning Response



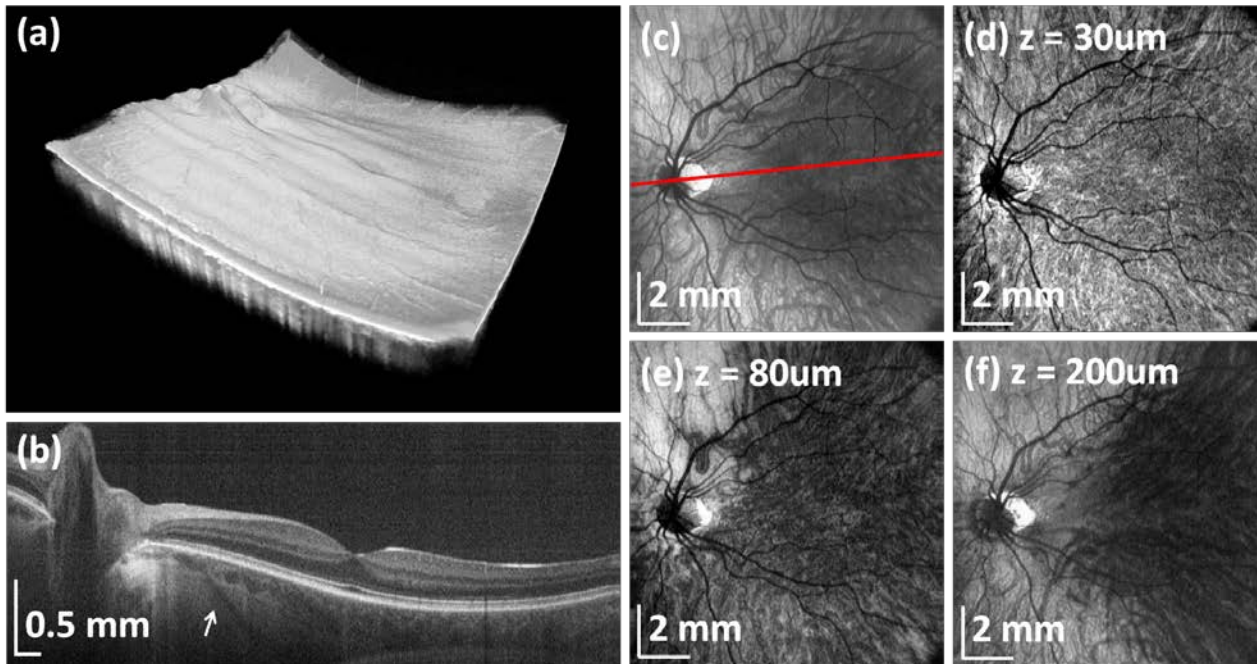
100-nm Dynamic Tuning Response



Electrostatic Actuator Frequency Response

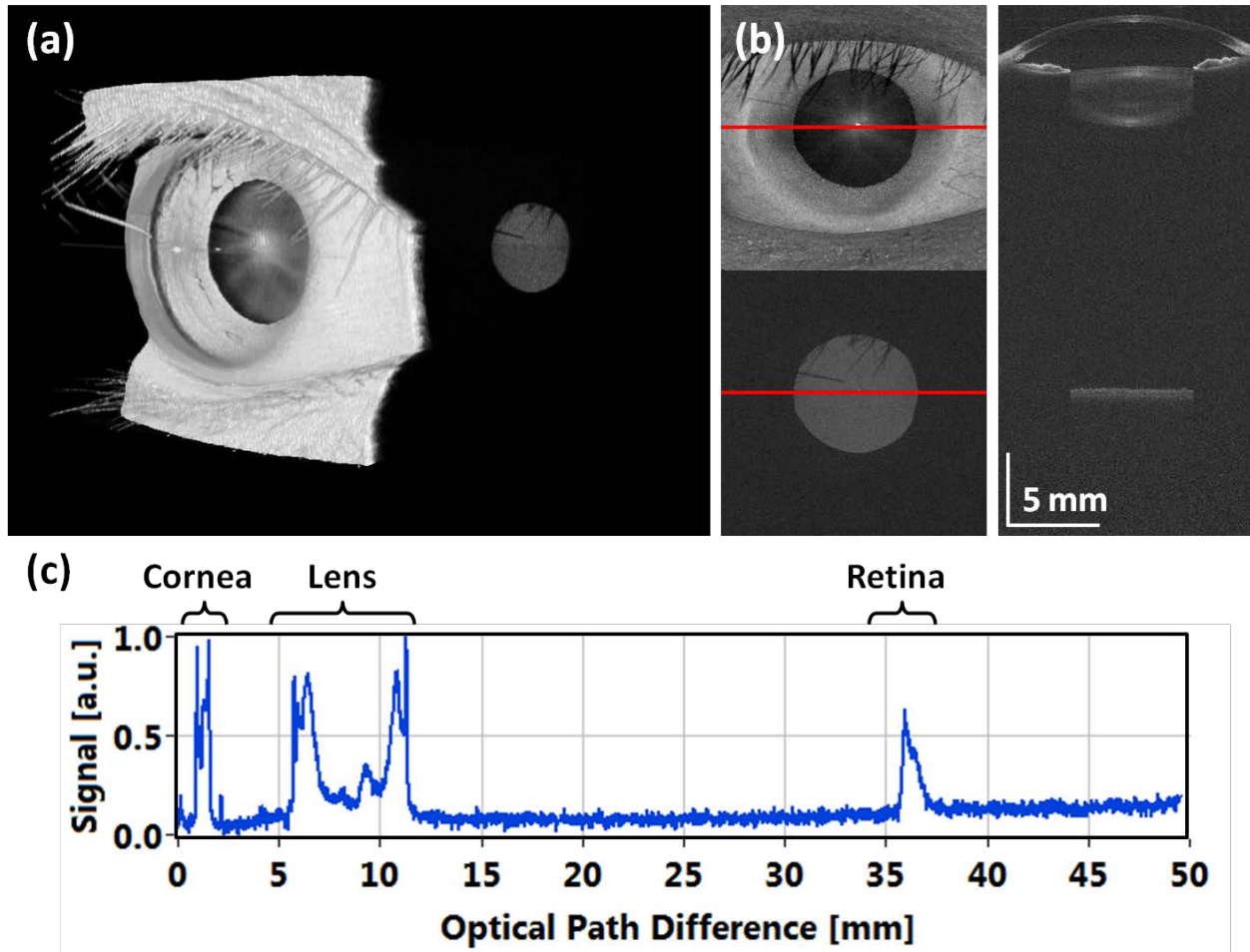


Wide-Field Choroidal (Sub-Retinal) Imaging



- (a) Rendering of volumetric wide-field OCT imaging data set
- (b) Cross-sectional image of choroid and sclera [red section line in (c)]
- (c-f) Projection images at depths of (d) 30 μm , (e) 80 μm , (f) 200 μm

Full Eye Imaging at 1060 nm



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Summary of Laser Properties

- Ultra-widely tunable optically pumped MEMS-VCSELs have been demonstrated for application in SS-OCT
 - 150 nm dynamic tuning range at 1310 nm
 - 100 nm dynamic tuning range at 1060 nm
- Actuator bandwidth in the 0.5 MHz range with well-behaved frequency response (near critically damped)
- Reasonable maximum tuning voltages (<60 V)
- Commercially viable wafer-scale fabrication procedure has been developed for dielectric electrostatic actuator
- Demonstration of state-of-the art SS-OCT performance

Path Forward

- Push FSR as wide as possible for maximum tuning
- Electrically injected devices for compact sources
- More operating wavelengths (850 nm and visible)
- Reliability studies on MEMS actuator structure
- Exploration of additional imaging applications
- High-speed transient spectroscopy demonstrations